IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Attn: APPLICATION BRANCH

Norio KIMURA et al.

Attorney Docket No. 2004 0201

Serial No. NEW

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Filed February 25, 2004

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POLISHING APPARATUS AND METHOD (Rule 1.53(b) Divisional of Serial No. 09/824,644, Filed April 4, 2001)

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

CLAIM OF PRIORITY UNDER 35 USC 119

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicants in the above-entitled application hereby claim the date of priority under the International Convention of Japanese Patent Application No. 2000-102669, filed April 4, 2000, and Japanese Patent Application No. 2000-163082, filed May 31, 2000, as acknowledged in the Declaration of this application.

Certified copies of said Japanese Patent Applications are of record in parent application Serial No. 09/824,644, filed April 4, 2001.

Respectfully submitted,

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